

Measurement issues of on-Silicon deembedding test structures in the Sub-THz range

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OUTLINE

Motivations

- mmW and Sub-mmW Applications
- Transistor HF Characterization Challenges

Sub-THz Silicon On-Wafer Calibration Kit

On-wafer Calibration Kit for Measurements up to 500 GHz

On-Wafer TRL Application up to 220 GHz

- Methodology
- Focus on Open-M1 de-embedding structure



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mmW and sub-mmW Applications

Millimeter and Sub-Millimeter Wave Frequency Ranges and Applications





mmW and sub-mmW Applications

Silicon-Germanium State-of-the-art Technologies

f _T /f _{max} 505/720 GHz [1] 250/370 GHz [2] 300/420 GHz [3] 320/370 GHz [4]		0.13µm SiGe BiCMOS HBT	90nm SiGe BiCMOS HBT	55nm SiGe BiCMOS HBT
	f _T /f _{max}	505/720 GHz [1] 250/370 GHz [2]	300/420 GHz [3]	320/370 GHz [4]

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- [1] B. Heinemann et al., IEDM 2016 (IHP)
- [2] J. Bock et al., BCTM 2015 (Infineon)
- [3] R.A. Camillo-Castillo et al., BCTM 2013 (IBM)
- [4] P. Chevalier et al., IEDM 2014 (STMicroelectronics)



Measurement accuracy





Relies on

Accurate compact models



On-wafer device measurements <u>S-parameters</u>

Extracted from/validated by



Measurement accuracy





Caliration & De-embedding issues

Standard procedure (2-step calibration)







Impedance Standard Substrate Source=Cascade Microtech



Calibration & De-embedding issues

Standard procedure (2-step calibration)





Calibration & De-embedding issues

Standard procedure (2-step calibration)







Calibration & De-embedding issues

Standard procedure (2-step calibration)



On-wafer calibration

- TRL is the "calibration of choice for metrological applications" [5]
 On wafer calibration kit development is needed
- On-wafer calibration-kit development is needed

[5] D.F. Williams, T-MTT March 2014



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Sub-THz On-Wafer TRL Calibration Kit

Implementation on Silicon Substrate (BiCMOS55 – STMicroelectronics)



Thru



Pad Open







Line (13-120 GHz)



Pad Load (for impedance correction)





Sub-THz On-Wafer TRL Calibration Kit

On-wafer TRL calibration kit for 140 - 500 GHz





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IMS S-parameters Measurement Benches





110GHz RF probes





325-500GHz RF probes



Methodology

Measurement versus EM simulation comparison



Measurement with different probe pitches and topologies



structures



REF



EM sim. of complete test structures



De-embedding structure

Open M1 structure and its terminal capacitances







De-embedding structure



- Open-M1 measured and simulated terminal Capacitances up to 220 GHz
 - TRL cal. meas. vs <u>intrinsic</u> structure sim.



Microscopic view of Picoprobe Probe (140 GHz – 220 GHz)





De-embedding structure : Influence of Probe design



- Open-M1 measured and simulated terminal Capacitance up to 220 GHz
 - TRL cal. meas. vs <u>intrinsic</u> structure sim.
 - Verification of C12 behavior



Cascade Infinity probe (140 GHz – 220 GHz)

Can Probe design influence result ?



De-embedding structure : Influence of Probe design



- Open-M1 measured and simulated terminal Capacitance up to 220 GHz
 - TRL cal. meas. vs intrinsic structure sim and TRL cal. sim .
 - Verification of C12 behavior



Microscopic view of Picoprobe Probe (140 GHz – 220 GHz)



Probe Model in HFSS

Probe design can influence result!





De-embedding structure : Influence of crosstalk b/w two ports/



- Open-M1 measured and simulated terminal Capacitance up to 220 GHz
 - TRL cal. meas. vs TRL cal. sim .
 - Effect of crosstalk b/w two ports in C12





De-embedding structure : Solution for improvement



- Probe design- CPW probe model in HFSS
 - New probe design TRL cal. sim predicts C12 behavior close to intrinsic sim.
 - Depending on probe design C12 can have only positive value





De-embedding structure : Solution for improvement



- Improvement in test structures design
 - Better design of test structures can lead C12 towards positive value



Conclusions & Perspectives

- On-wafer TRL calibrated measurements for de-embedding structure up to 220 GHz
 - → Probes of different pitches and topologies → some differences
- EM simulation of intrinsic and complete structures
 Better agreement with measurements with complete structures simulation
- ➡ Influence of RF pad design and probes on TRL calibration
- Perspectives:
 - → Pad design improvement through layout design using EM simulation
 - → Application to SiGe HBT characterization up to 500 GHz





THANK YOU !









